

FIG. 1

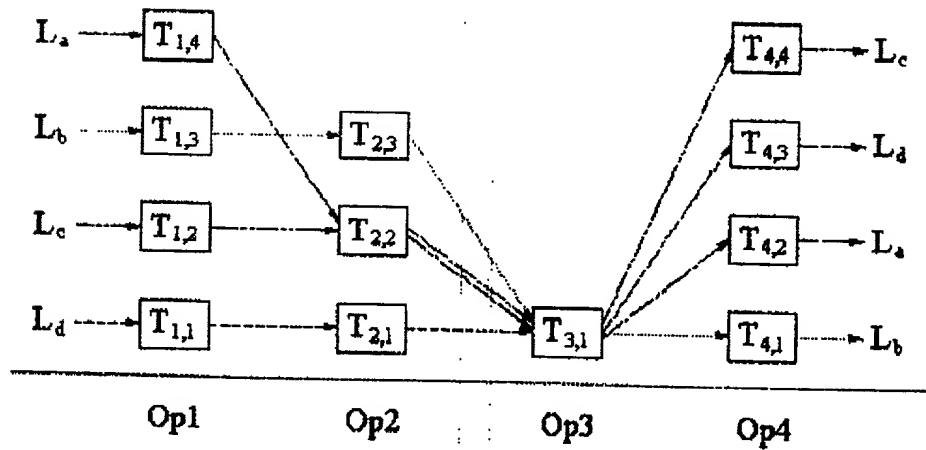


FIG. 2

20250202 09:00:00

	Lot: L_a	Process Flow=PF101					Da
		operation	Op1	Op2	Op3	Op4	---
Ld_a	tool	$T_{1,1}$	$T_{2,1}$	$T_{3,1}$	$T_{4,1}$	---	---
	wafer	$W_{a,1}$	$W_{a,2}$	$W_{a,3}$	$W_{a,4}$	---	
Yd_a	yield	$Y_{a,1}$	$Y_{a,2}$	$Y_{a,3}$	$Y_{a,4}$	---	

FIG. 3

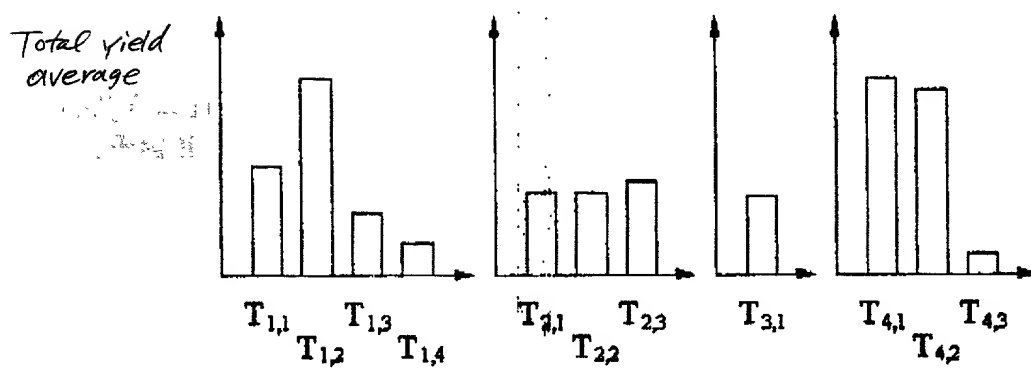


FIG. 4